## 多接合太陽電用 GaAs 系トンネルダイオードの MOVPE 成長 MOVPE growth of GaAs-based tunneling diode for multiple junction solar cells ッソダーバンル・ハッサネット<sup>1</sup>, 渡辺健太郎<sup>1</sup>, 杉山正和<sup>1-2</sup>, 中野義昭<sup>2</sup> <sup>o</sup> H. Sodabanlu<sup>1</sup>, K. Watanabe<sup>1</sup>, M. Sugiyama<sup>1-2</sup>, Y. Nakano<sup>2</sup> <sup>1</sup>東大先端研 RCAST, The Univ. of Tokyo, <sup>2</sup>東大院工 School of Engineering, The Univ. of Tokyo

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## **1** Introduction

The recent record conversion efficiency of 46% has been realized by InGaP/GaAs/InGaAsP/InGaAs 4-junction (4J) solar cells fabricated by direct wafer bonding technique [1]. Our group reported in this community about the optimization of metalorganic vapor phase epitaxy (MOVPE) growth for InGaAsP/InGaAs dual junction solar cells [2]. In this work, we investigated and optimized the growth conditions for GaAs-based tunneling diodes (TDs) for InGaP/GaAs electrical interconnection as a further step toward the fabrication of 4J solar cells.

## 2 Experimental details, results and discussion

The experiment was carried out using a planetary MOVPE reactor. Due to the limitation of our MOVPE system, the dopant sources for n-type and p-type doping were limited only to diethyltelluride (DETe) and dimethylzinc (DMZn), respectively. The investigated structure consisted of 500-nm-thick p-GaAs contact layer on p+/n+ GaAs TDs, 100-nm-thick each, and 500-nm-thik n-GaAs buffer grown on (001) n-GaAs substrates (Si  $2x10^{18}$  cm<sup>-3</sup>). The in-situ surface temperature of GaAs wafer was observed by emissivity-corrected pyrometry. First, two GaAs TDs were fabricated using the identical growth conditions excepting that the first sample was grown with a standard surface temperature of 570 °C.

Figure 1(a) shows the profiles of active carrier concentration in GaAs TDs evaluated by electrochemical capacitance-voltage measurement.

Obviously, by decreasing the surface temperature, the carrier concentrations of both Te and Zn doped GaAs could be greatly enhanced. These results can be explained by a decrease in dopant desorption from GaAs surface at a lower temperature. Applying these carrier profiles to a simulation, the energy band diagrams of both samples were calculated and plotted in Fig. 1(b). Owing to higher carrier concentrations, the junction width between p+ and n+ GaAs was clearly narrower in the case of 570 °C grown sample. After depositing metal electrodes, the samples were mesa-etched to have an area of  $4.7 \text{ mm}^2$ . The current-voltage (I-V) characteristics of both GaAs TDs were plotted in Fig. 1(c). Note that, the current was limited to 0.1 A in this measurement, and the peak tunneling current could not be evaluated here. Nevertheless, the 600 °C grown TD obviously exhibits a diode behavior, while the other has ohmic like I-V curve with a sheet resistivity of 14 m $\Omega \bullet cm^2$ . Further studies and optimizations have been under investigation including the implementation of wide bandgap materials, and growth parameters.

## **3** Summary

The low temperature growth is proved to be beneficial for the growth of highly doped GaAs-based TDs. Further studies and optimizations have been under investigation.

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[1] F. Dimroth et al., J. Photovoltaics **6**, 343, 2016.

[2] H. Sodabanlu et al., 78th JSAP, 7p-S21-15, 2017



Fig. 1 (a) Carrier profiles of GaAs TDs grown at different temperatures (b) band diagrams simulated using data from Fig. 1(a) and (c) current-voltage curves of GaAs TDs grown at different temperatures